

Patent

Custom No.: 31561

Docket No.: 10606-US-PA

Application No.: 10/604,392

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Applicant : Chou et al.
Application No. : 10/604,392
Filed : 2003/7/17
For : GAS DISTRIBUTING SYSTEM FOR DELIVERING PLASMA
GAS TO A WAFER REACTION CHAMBER
Art Unit : 1763
Examiner : Lund, Jeffrie Robert

TRANSMITTAL LETTER

002-1-703-872-9306

(Via fax : 1+5 pages)

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Assistant Commissioner for Patents
Alexandria, VA 22314

JUN 02 2005

Dear Sir,

In response to the Office Action dated May 4, 2005(Paper No.: 20050429), please find the Response to Office Action, in 5 pages.

I believe that no fee is incurred. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-2620 (Order No.: 10606-US-PA).

Thank you for your assistance in the subject matter. If you have any questions, please feel free to contact me.

Respectfully Submitted,
JIANQ CHYUN Intellectual Property Office

Date : June 2, 2005

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